



Attorney's Docket No.: 42P17283

Patent

*7/11/07*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Michael McSwiney et al.

U.S. Serial No: 10/750,062

Filed: December 30, 2003

For: METHOD AND APPARATUS FOR LOW  
TEMPERATURE SILICON NITRIDE  
DEPOSITION

Examiner: Turocy, David P.

Art Unit: 1762

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage in an envelope addressed to the Commissioner for Patents, PO Box 1450, Alexandria, Virginia 22313-1450

on July 11, 2007  
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Teresa Mattox 7/11/07  
Signature Date

Commissioner of Patents and Trademarks  
P.O. Box 1405  
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**RESPONSE TO SPECIES ELECTION**

Sir:

In response to the Election Requirement mailed February 23, 2007, applicant(s) hereby elects to prosecute Group I claims 1-20, drawn to a method for depositing a silicon film. Additionally, Applicant elects Species A, the specific silicon precursor/source. It is Applicant's understanding that at least claims 1-11 and 13-20 are readable thereon. Accordingly, claims 21-27 are withdrawn from consideration.

If there are any additional charges, please charge Deposit Account No. 02-2666.

Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN

Date: July 11, 2007

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